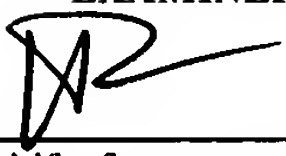
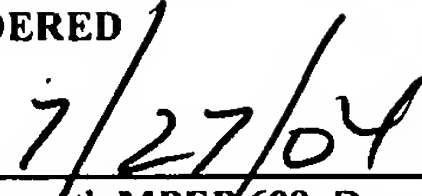
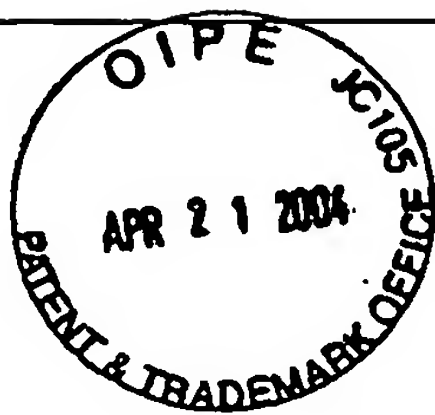


				ATTY. DOCKET NO.:		APPLICATION NO.:	
				4717-8100			
				APPLICANT:			
				Laurent FILIPOZZI et al			
				FILING DATE:		GROUP:	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA		5,996,594	12/1999	Roy et al.	134	1.3	
AB		6,336,945 B1	1/2002	Yamamoto et al.	51	309	
AC							
AD							
AE							
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
	AF						
	AG						
	AH						
	AI						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
	BD						
	BE						
	BF						
EXAMINER				DATE CONSIDERED			
							
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							



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10/621, 122

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Laurent FILIPOZZI et al

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3723

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AF							
	AG							
	AH							
	AI							

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

	AJ	Michael L. Free, XP-002266271, "Using Surfactants in iron-based CMP slurries to minimize residual particles", Surface Chemistries, Micromagazine (1998)
	AK	
	AL	

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.